

IN THE CLAIMS:

Please amend the claims as follows.

1. (Amended) A positioning device [having] for a lithographic

apparatus, comprising:

a guiding surface extending parallel to an X-direction and parallel to a Y-direction[,];

a first object holder and a second object holder which are each adapted to be guided over the guiding surface and are each displaceable parallel to the X-direction and parallel to the Y-direction from a first position into a second position[,]; and

a displacement system [for displacing] constructed and arranged to displace the first object holder and the second object holder over the guiding surface, [characterized in that]

wherein the displacement system comprises a first displacement unit and a second displacement unit to which the first object holder and the second object holder can be coupled alternately, the first displacement unit being suitable for displacing the object holders from the first position into an intermediate position between the first position and the second position, and the second displacement unit being suitable for displacing the object holders from the intermediate position into the second position.

2. (Amended) A positioning device as claimed in claim 1, [characterized in that] wherein the first and second displacement units each comprise an X-motor having a first part extending parallel to the X-direction and a second part which is displaceable along the first part of the X-motor and can be coupled alternately to the first object holder and to the second object holder, and two Y-motors each having a first part extending parallel to the Y-direction and a second part which is displaceable along the first part of the relevant Y-motor, the first part of the X-motor of each displacement unit being connected to the second parts of the two Y-motors of the relevant displacement unit.

3. (Amended) A positioning device as claimed in claim 2, [characterized in that] wherein the first parts of the Y-motors of the two displacement units are connected to a common balancing unit which is guided relative to a base of the positioning device so as to be displaceable parallel to the X-direction and parallel to the Y-direction and to be rotatable about an axis of rotation extending perpendicularly to the X-direction and the Y-direction.

4. (Twice Amended) A positioning device as claimed in claim 1, [characterized in that] wherein the object holders each comprise a basic part which is guided over the guiding surface and [can] adapted to be coupled to the displacement

units, and an object table which is displaceable relative to the basic part by [means of] an actuator unit of the relevant object holder.

5. (Amended) A positioning device as claimed in claim 4,

[characterized in that] wherein the object table of each of the object holders is displaceable relative to the basic part parallel to the X-direction, parallel to the Y-direction, and parallel to a Z-direction extending perpendicularly to the X-direction and the Y-direction, and is pivotable relative to the basic part about a first pivot axis extending parallel to the X-direction, a second pivot axis extending parallel to the Y-direction, and a third pivot axis extending parallel to the Z-direction.

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(Twice Amended)

A lithographic device [provided

with] comprising:

a radiation source[.];

a mask holder[.];

a focusing unit having a main axis[.];

a characterization unit[.]; and

a positioning device[, said positioning device] comprising;

a guiding surface extending parallel to an X-direction, which is perpendicular to the main axis, and parallel to a Y-direction, which is perpendicular to the X-direction and this main axis,

a first substrate holder and a second substrate holder which are each guided over the guiding surface and are each displaceable parallel to the X-direction and parallel to the Y-direction from a first position into a second position which is near the focusing unit, and

a displacement system [for displacing] constructed and arranged to displace the first substrate holder and the second substrate holder over the guiding surface, [characterized in that the positioning device of the lithographic device is a positioning device as claimed in claims 1,]

wherein the displacement system comprises a first displacement unit and a second displacement unit to which the first substrate holder and second substrate holder can be coupled alternately, the first displacement unit being suitable for displacing the substrate holders from the first position into an intermediate position between the first position and the second position, and the second displacement unit being suitable for displacing the substrate holders from the intermediate position into the second position.

[wherein each of the object holders of the positioning device is a substrate holder of the lithographic device,] and

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wherein the first position of the [object] substrate holders is a characterization position which is present near the characterization unit.

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Please add the following new claims 7-10.

8-7.

A lithographic device as claimed in claim ⁷~~6~~, wherein the first and second displacement units each comprise an X-motor having a first part extending parallel to the X-direction and a second part which is displaceable along the first part of the X-motor and can be coupled alternately to the first substrate holder and to the second substrate holder, and two Y-motors each having a first part extending parallel to the Y-direction and a second part which is displaceable along the first part of the relevant Y-motor, the first part of the X-motor of each displacement unit being connected to the second parts of the two Y-motors of the relevant displacement unit.

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8.

A lithographic device as claimed in claim ⁸~~7~~, wherein the first parts of the Y-motors of the two displacement units are connected to a common balancing unit which is guided relative to a base of the positioning device so as to be displaceable parallel to the X-direction and parallel to the Y-direction and to be rotatable about an axis of rotation extending perpendicularly to the X-direction and the Y-direction.